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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/361,980
Filing Date: July 28, 1999
Applicant: Ito et al.
Group Art Unit: 1765
Examiner: Lynette T. Umez-Eronini
Title: Method of Etching Metallic Thin Film Resistor
Attorney Docket: 4041J-000439

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DEC 09 2002
TC 1700

Commissioner of Patents and Trademarks
Washington, D.C. 20231

AMENDMENT AND PETITION FOR EXTENSION OF TIME

Sir:

In response to the Office Action mailed July 30, 2002, Paper No. 15, please amend and reconsider the above referenced patent application as follows.

Applicant hereby petitions under the provisions of 37 C.F.R. § 1.136(a) for an one (1) month extension of time in which to respond to the outstanding Office Action and includes a fee as set forth in 37 C.F.R. § 1.17(a) with this response for such extension of time.

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